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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/594,510	06/16/2000	Alan G. Wood	M4065.0184/P184	2407

24998 7590 08/09/2005

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EXAMINER

LUU, CHUONG A

ART UNIT	PAPER NUMBER
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2818

DATE MAILED: 08/09/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

H.A

Office Action Summary

Application No.

09/594,510

Applicant(s)

WOOD ET AL.

Examiner

Chuong A. Luu

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 03 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 29 April 2005.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-23 and 35-40 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-23 and 35-40 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- * See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date <u>2/15/2005</u> . | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Response to Arguments

Applicant's arguments with respect to claims 1-23 and 35-40 have been considered but are moot in view of the new ground(s) of rejection.

WITHDRAWN

The indicated allowability of claims 19-23 is withdrawn in view of the newly discovered reference(s) to Horiuchi et al. (U.S. 6,297,553 B1) and Smith (U.S. 5,808,874).. Rejections based on the newly cited reference(s) follow.

PRIOR ART REJECTIONS

Statutory Basis

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

The Rejections

Claim 19 is rejected under 35 U.S.C. 102(b) as being anticipated by Smith (U.S. 5,808,874).

Smith discloses a microelectronic assembly with

(19) aligning a plurality of semiconductor devices in a semiconductor wafer with respect to openings in a dielectric tape;

subsequently, connecting said semiconductor devices in said wafer to ball grid arrays on said dielectric tape;

simultaneously dicing said wafer and said dielectric tape (see column 4, lines 1-17 and column 7, lines 1-9. Figure 1);

PRIOR ART REJECTIONS

Statutory Basis

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

The Rejections

Claim 20 is rejected under 35 U.S.C. 103(a) as being unpatentable over Smith (U.S. 5,808,874) in view of Gaynes et al. (U.S. 6,165,885).

Smith teaches everything above except for wherein said wafer is optically aligned with respect to said dielectric tape. However, Gaynes discloses an electronic component with (20) wherein said wafer is optically aligned with respect to said dielectric tape (see column 18, lines 51-65) It would have been obvious to one having

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ordinary skill in the art at the time the invention was made to modify the teaching of Smith (in accordance with the teaching of Gaynes) to optically aligned with respected to the dielectric layer during fabrication of a semiconductor device

Claims 21-23 are rejected under 35 U.S.C. 103(a) as being unpatentable over Smith (U.S. 5,808,874) in view of Smith (U.S. 6,300,149).

Smith' 874 teaches everything above except for wherein said wafer is magnetically aligned with respected to said dielectric tape; wherein oppositely charged magnetically elements are provided on said wafer and said tape; further comprising the step of locating a magnetic ring in a charged slot. However, Smith'149 discloses an integrated circuit with **(21)** wherein said wafer is magnetically aligned with respected to said dielectric tape (see column 4, lines 30-67); **(22)** wherein oppositely charged magnetically elements are provided on said wafer and said tape (see column 4, lines 30-67); **(23)** further comprising the step of locating a magnetic ring in a charged slot (see column 4, lines 30-67). It would have been obvious to one having ordinary skill in the art at the time the invention was made to modify the teaching of Smith'874 (in accordance with the teaching of Smith's149) to magnetically aligned with respected to the dielectric layer during fabrication of a semiconductor device.

PRIOR ART REJECTIONS

Statutory Basis

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

The Rejections

Claims 1-18 and 35-40 are rejected under 35 U.S.C. 103(a) as being unpatentable over Horiuchi et al. (U.S. 6,297,553 B1) in view of Smith (U.S. 5,808,874).

Horiuchi discloses a semiconductor device with

Respect to claims:

(1) forming conductive structures (20) in contact with a top surface of a dielectric substrate (10) (see Figure 2);

subsequently, forming a layered assembly by attaching a wafer (12) to said dielectric substrate (10), such that said conductive traces (20) are in electrical communication with semiconductor devices in said wafer (12) (see Figure 2);

forming input/output devices (26) in contact with said conductive traces (20) (see Figure 2);

subsequently, dicing said layered assembly (see column 7, lines 1-9);

(2) further comprising the step of connecting said semiconductor devices to input/output devices (see Figure 2);

(5) wherein said step of forming said layered assembly includes the step of adhering said wafer to said dielectric substrate (see Figure 2);

(6) further comprising the step of electrically connecting said semiconductor devices to ball grid arrays on said dielectric substrate (see Figure 2E);

(7) wherein said connecting step comprises the step of locating wire bonds in openings through said dielectric substrate (see Figure 2);

(8) wherein said connecting step comprises the step of connecting solder bumps on said wafer to circuit traces on said dielectric substrate (see Figure 2);

(10) further comprising the step of providing an electrode pad in said layered assembly (see Figure 2);

(11) providing conductive structures in contact with a top surface of a dielectric substrate (see Figure 2);

subsequently, forming a layered assembly by attaching a wafer and said dielectric substrate (see Figure 2);

placing ball grid arrays in contact with said conductive structures (see Figure 2);

connecting semiconductor devices in said semiconductor wafer to said ball grid arrays (see Figure 2);

subsequently, dicing said layered assembly (see column 7, lines 1-9);

(12) wherein said forming step comprises the step of adhering said wafer to said metal layer (see Figure 2);

(13); (14) wherein said connecting step comprises the step of locating wire bonds in openings through said dielectric substrate (see Figure 2);

(15) wherein said connecting step comprises the step of connecting solder bumps on said wafer to conductive traces on said dielectric substrate (see Figure 2);

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(16) further comprising the step of connecting said traces to conductive vias extending through said dielectric substrate (see Figure 2).

(18) further comprising the step of testing said semiconductor devices through said ball grid arrays (see Figure 2);

(35) connecting said semiconductor devices to respective ball grid arrays (60) located on said substrate (see Figure 2);

(37) further comprising the step of singulating packages from said wafer and said substrate (see column 7, lines 1-9);

(36); (38) further comprising the step of segregating defective packages from other packages (see column 7, lines 1-9).

Horiuchi discloses everything above except for wherein said testing is conducted through said input/output devices; adhering said wafer to a flexible substrate and further comprising the step of attaching said dielectric tape to said wafer by applying heat or pressure to the assembly. However, Smith discloses a microelectronic assembly with **(3)** wherein said testing is conducted through said input/output devices (see column 13, lines 12-24); **(4)** further comprising the step of discarding one or more defective packages (see column 5, lines 20-25); **(9); (17)** wherein said dicing step is performed by a saw (see column 11, line 20-23); **(11)**.... a stiff metal layer (see column 9, lines 3-24); **(35)** adhering said wafer to a flexible substrate (see column 3, lines 54-55); testing said semiconductor devices through said ball grid arrays (see column 13, lines 12-24); **(39)** further comprising the step of attaching said dielectric tape to said wafer by applying heat or pressure to the assembly (see column 7, lines 25-64); **(40)** further

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comprising the step of evacuating gas from said assembly (see column 10, lines 51-63).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to modify the teaching of Horiuchi (in accordance with the teaching of Smith) to attach the dielectric tape to said wafer by applying heat and pressure to the assembly; and further comprising the step of evacuating gas from said assembly during fabrication of a semiconductor device. Although, Horiuchi's reference is silent the step of testing semiconductor device; it would have been obvious that the testing should be taken place prior to further fabricating a semiconductor device. Doing so would facilitate the manufacture of the semiconductor device and reduce the time and cost by determining the defective device prior to complete the semiconductor device.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Chuong A. Luu whose telephone number is (571) 272-1902. The examiner can normally be reached on M-F (6:15-2:45).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David C. Nelms can be reached on (571) 272-1787. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

A handwritten signature in black ink, appearing to read 'C. Luu', is positioned above the printed name and title.

Chuong Anh Luu
Patent Examiner
August 5, 2005